

**Instrumentation Seminar**  
**March 17, 2004 at BNL**

# **Silicon Radiation Detectors**

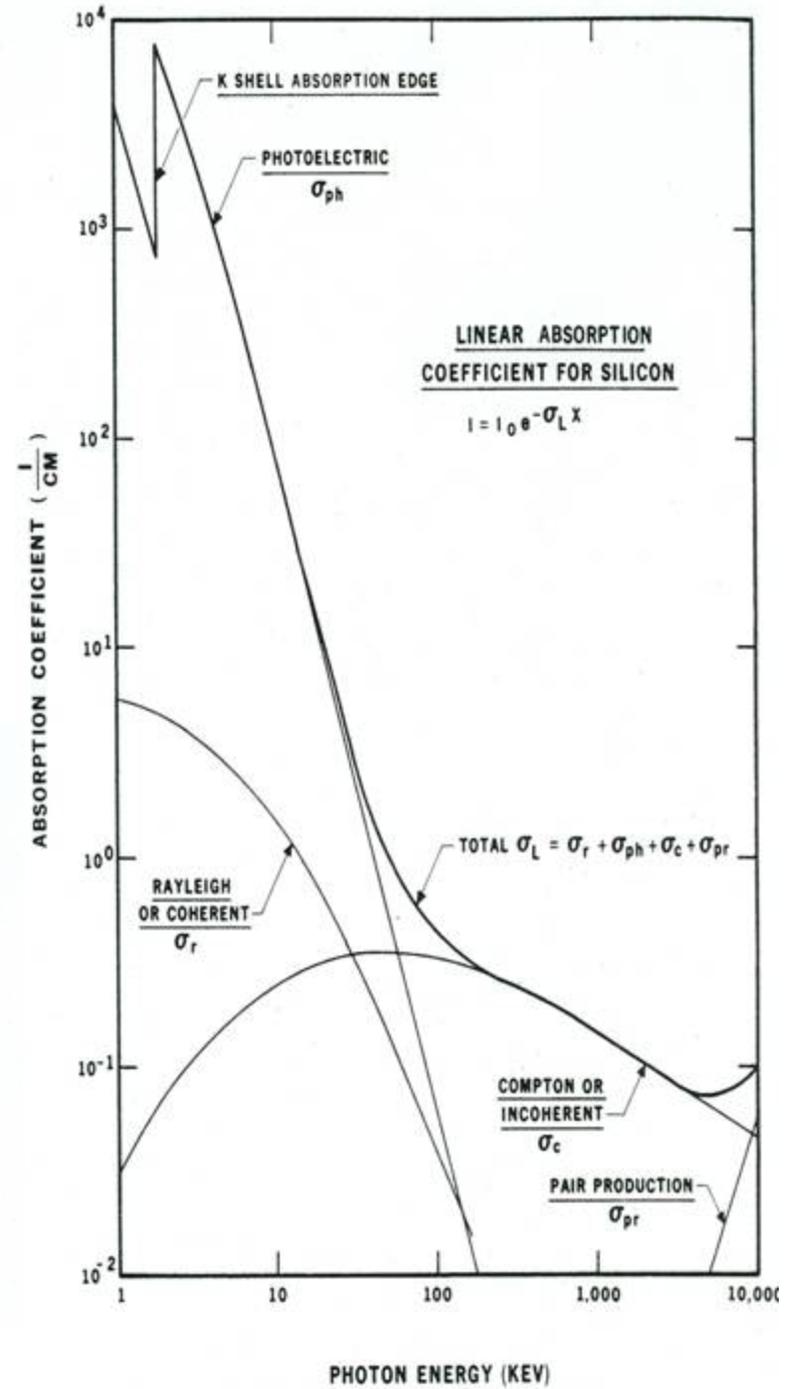
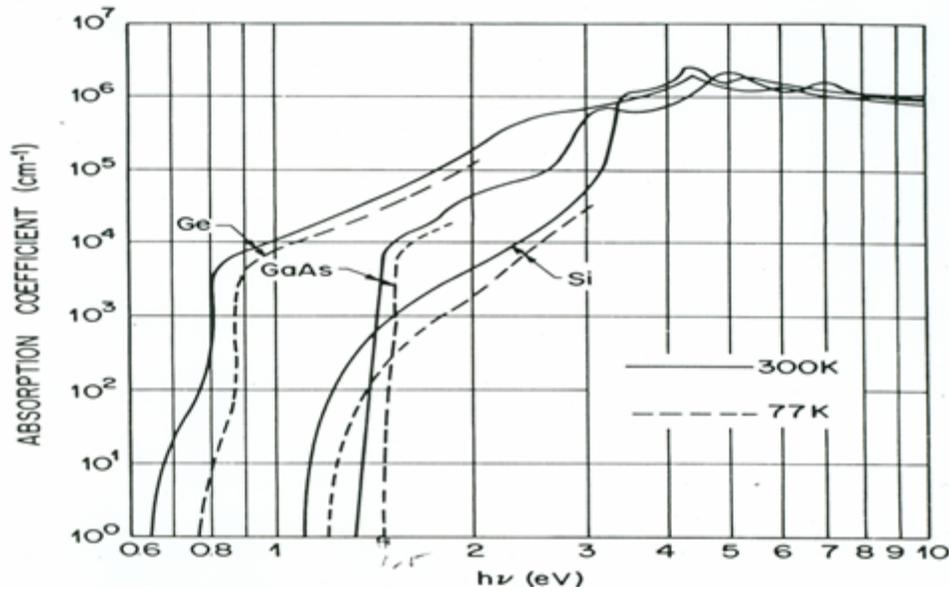
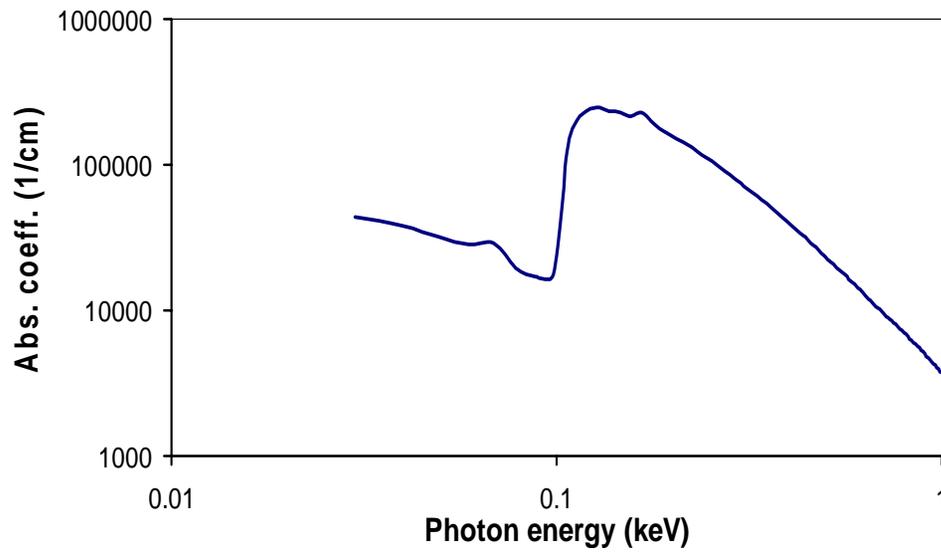
Pavel Rehak

Brookhaven National Laboratory

# Outline of the Talk

- Silicon age (after the stone and iron ages)
- Silicon as the detection medium
- Detector grade silicon
- Simple diode silicon detectors
- Introduction of planar process for Si detectors
- Modern detector structures
- Perspectives

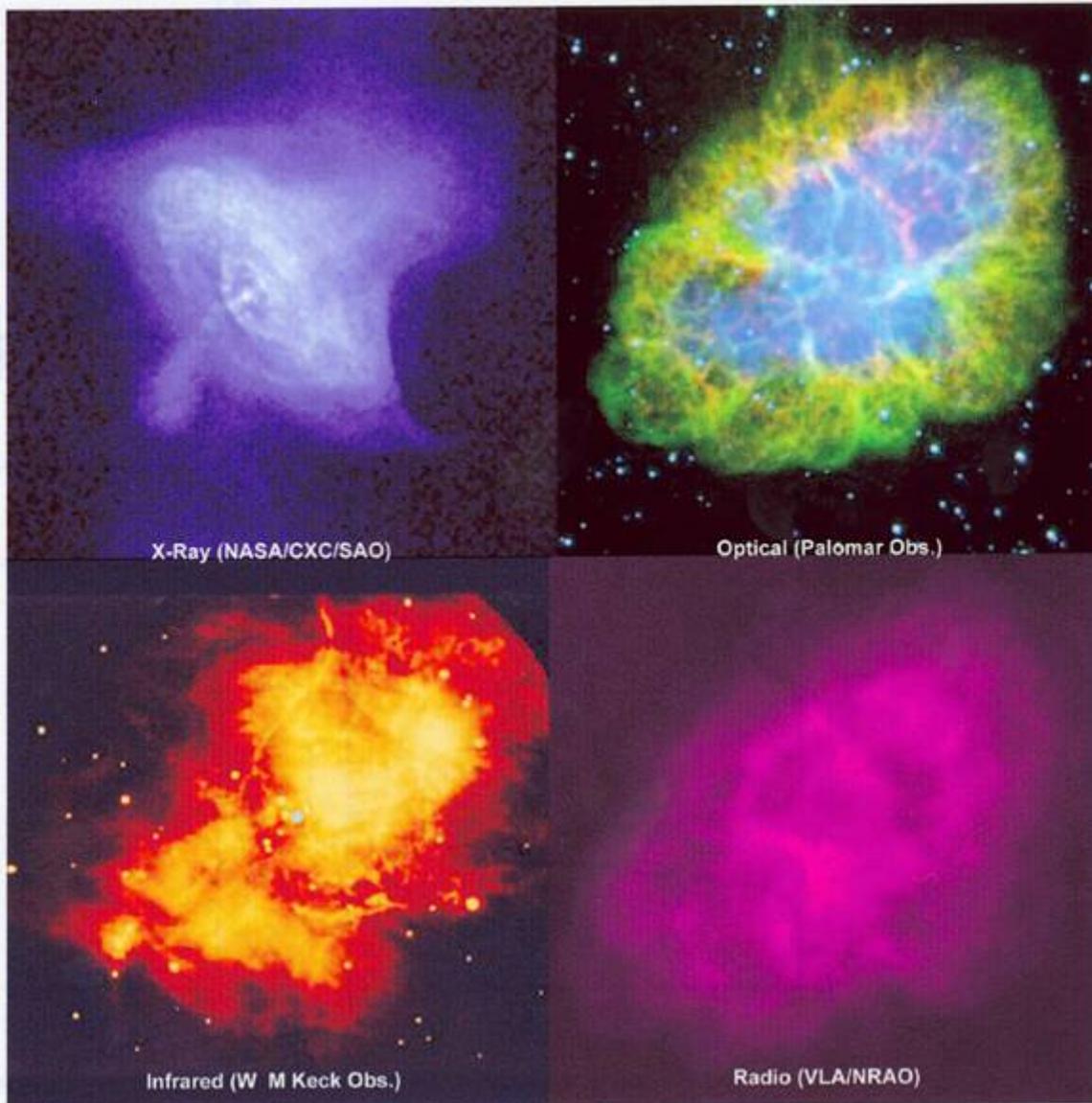
### Linear absorption coefficient



# *Chandra X-Ray Observatory*

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## Crab Nebula



$$\sigma_{Si}^2 = F \cdot E_{\text{photon}} w$$

$$ENC_{\text{par}}^2 = qI_{\text{leak}} \int_{-\infty}^{\infty} h(t)^2 dt \approx qI_{\text{leak}} t_{\text{peak}}$$

$$ENC_{\text{series}}^2 = \frac{1}{2} e_n^2 C_t^2 \int_{-\infty}^{\infty} [h'(t)]^2 dt \approx e_n^2 C_t^2 / t_{\text{peak}}$$

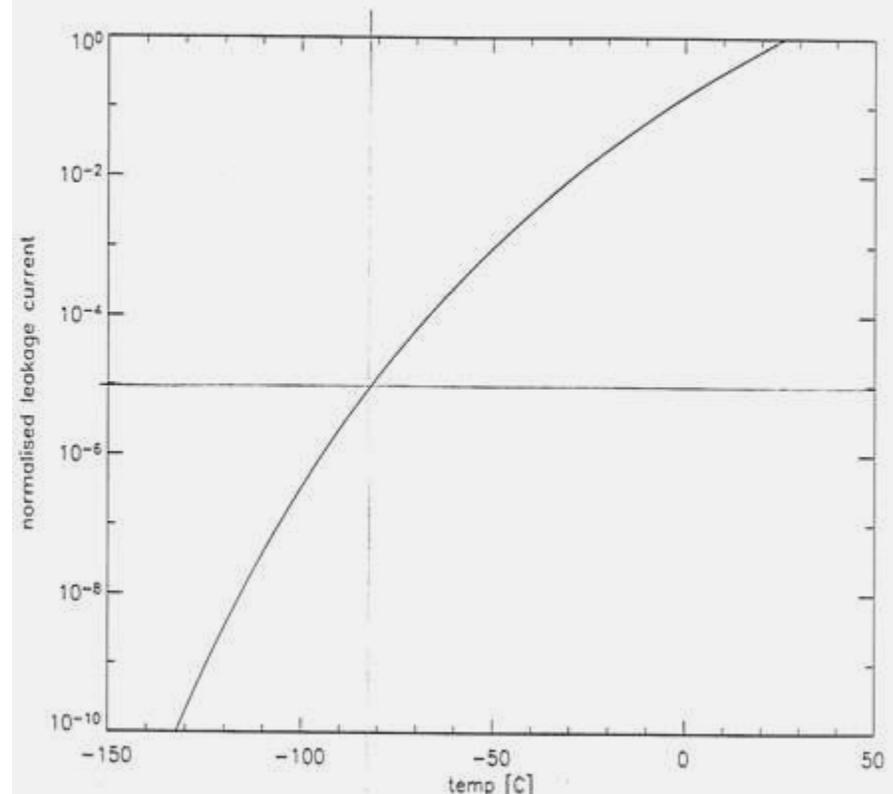
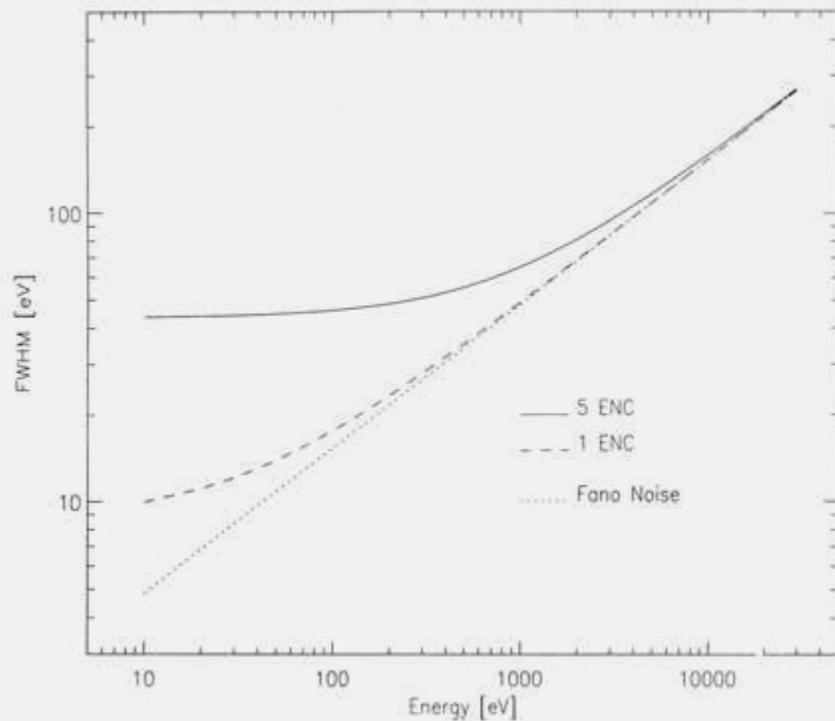
$$t_{\text{peak}}^{(\text{optimal})} = e_n C_t / \sqrt{q \cdot I_{\text{leak}}}$$

$$w = 3.62 eV$$

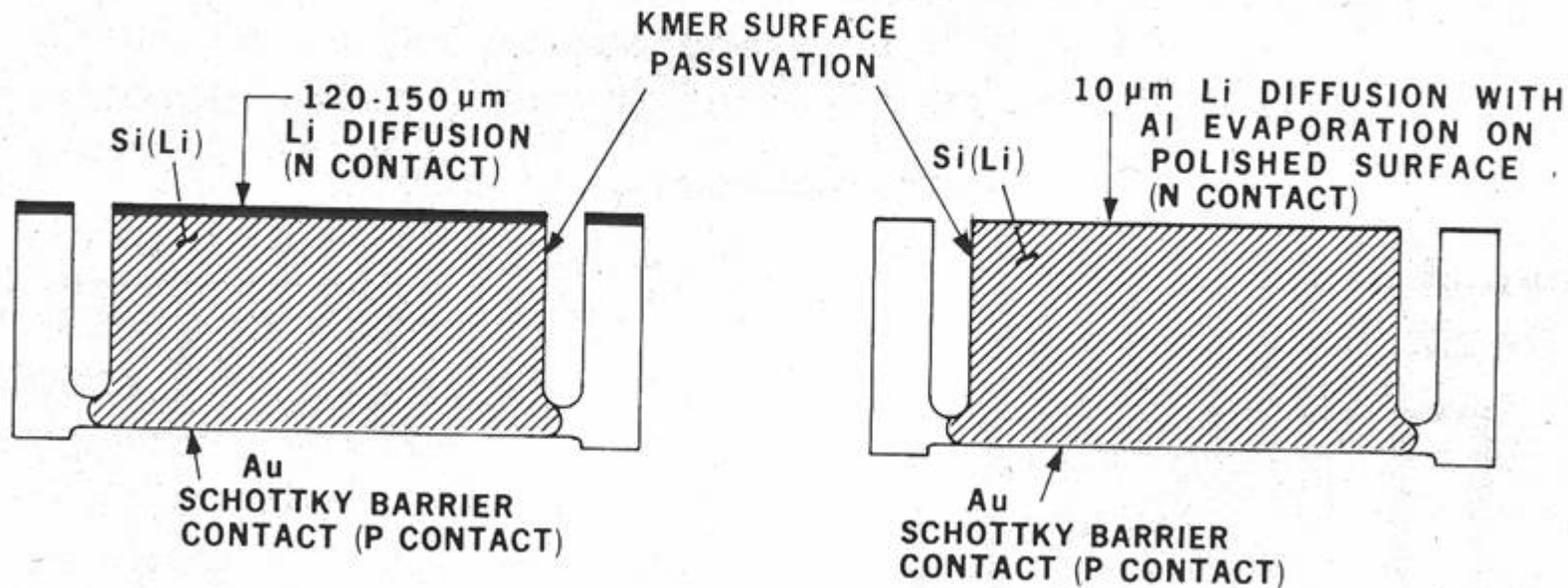
Leakage Current:  $i_{leak} = q \cdot n_i / (2 \cdot \tau)$

Where  $n_i$  is the density of carrier in intrinsic silicon,  $\tau$  is the life time and  $N_t$  the density of traps in silicon bulk.

$$n_i \propto \exp(-E_{gap} / (2kT))$$
$$\tau \cong 1 / (\sigma \cdot v_{th} \cdot N_t)$$



# Si(Li) detectors before 1982



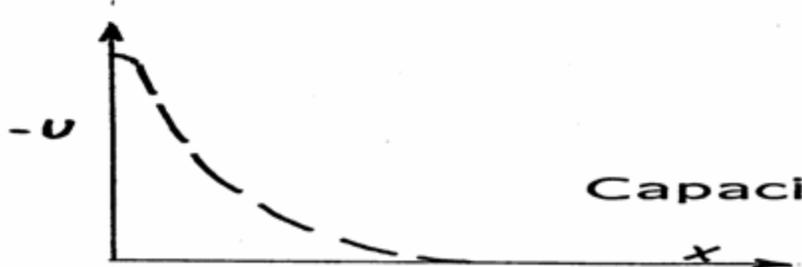
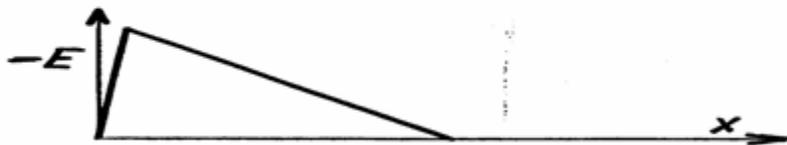
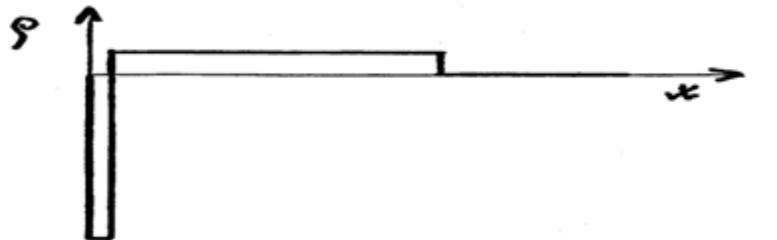
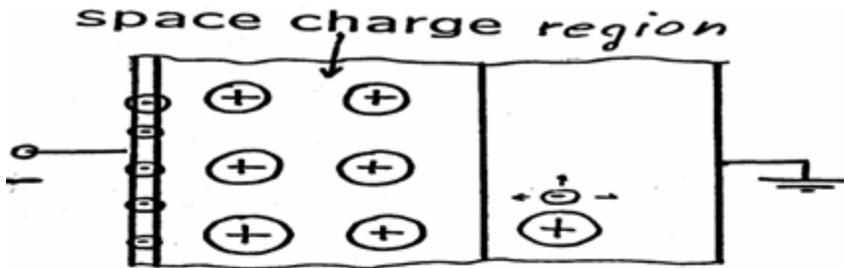
$$C_{\text{det}} = \epsilon_0 \cdot \epsilon_r \cdot S / d$$

$$(\partial^2 / \partial x^2 + \dots + \partial^2 / \partial z^2)U = -q \cdot N_{\text{dop}} / (\epsilon_0 \cdot \epsilon_r) = \rho$$

$$-U = 1/2 \cdot \rho \cdot z^2$$

# Junction detector

- Abrupt one sided junction (rectifying bias)



space charge density

$$\rho = qN_D$$

$N_D$  donor density

Eq. of electrostatics

$$\text{div} E = \frac{\rho}{\epsilon}$$

$$\frac{dE}{dx} = \frac{\rho}{\epsilon}$$

E linear

$$E = -\frac{dV}{dx}$$

V parabolic

Depletion length  $d$

$$d = \sqrt{\frac{2\epsilon V}{qN_D}}$$

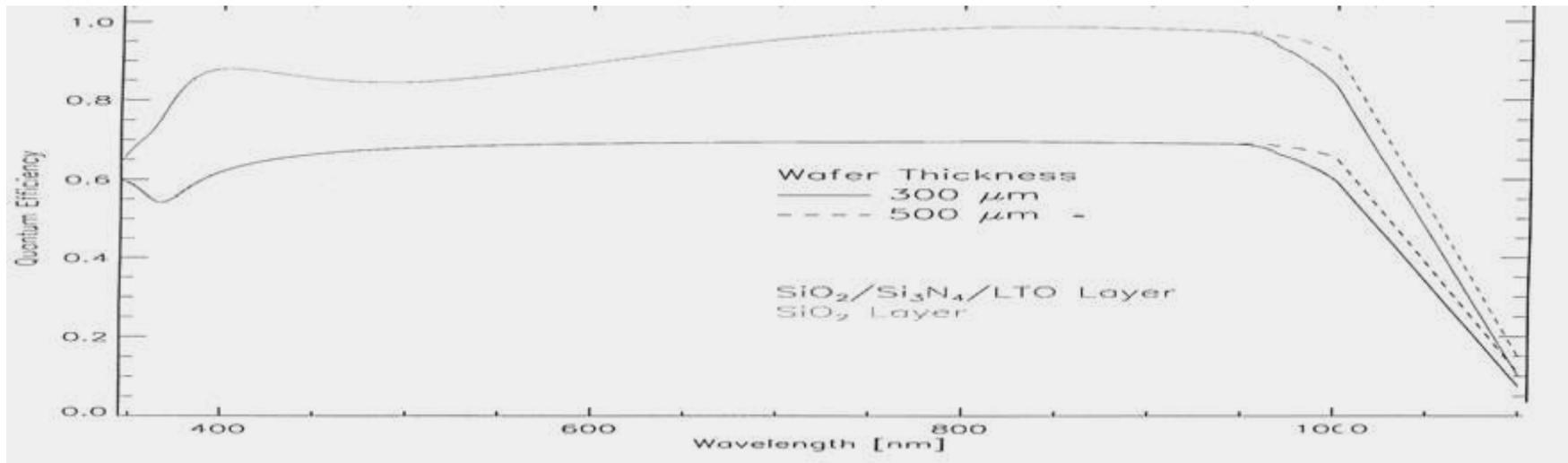
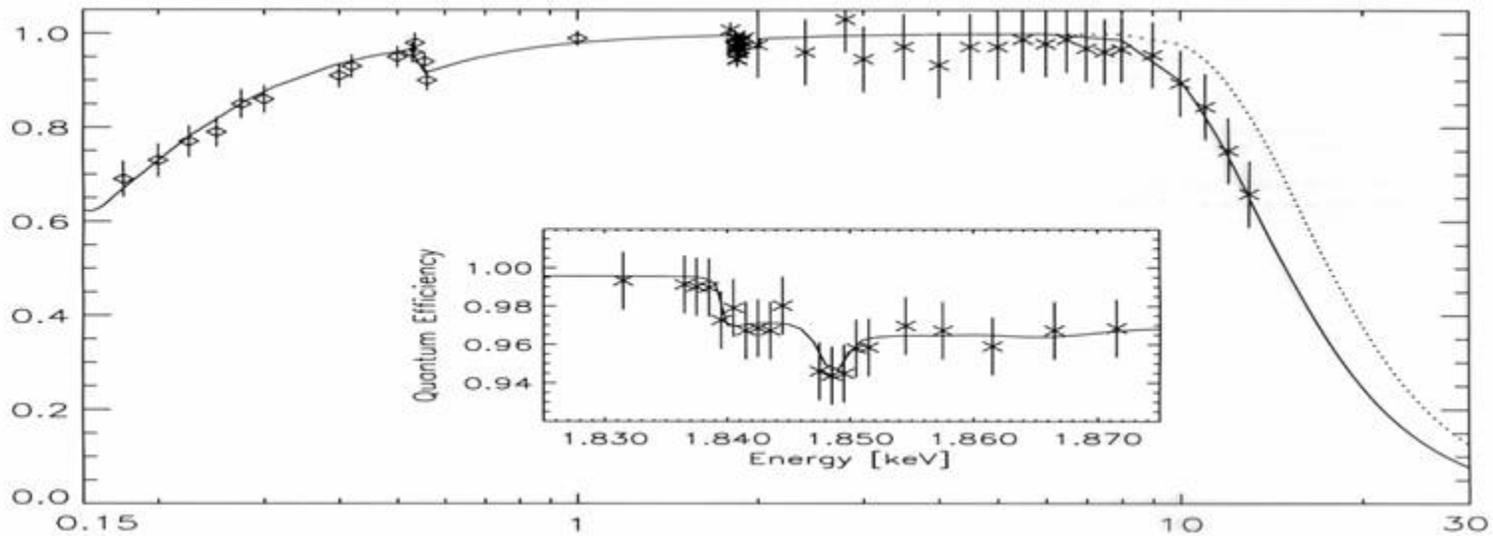
Capacitance =  $\frac{\epsilon}{d} = \sqrt{\frac{q\epsilon N_D}{2V}}$  prop.  $\frac{1}{\sqrt{V}}$

# Developments in silicon detectors after 1982

- 1) Planar technology (from IC production) introduced to production of silicon detectors
- 2) Segmentation of the surface to form multi-detector
- 3) Application of the field parallel to the detector surface
- 4) Taking advantage of the field produced by ionized impurities (donors and acceptors).
- 5) Implementation of transistors within detector

Planar tech. limited thickness of the detector up to .5mm

# Efficiencies of planar detectors



# Silicon strip detector

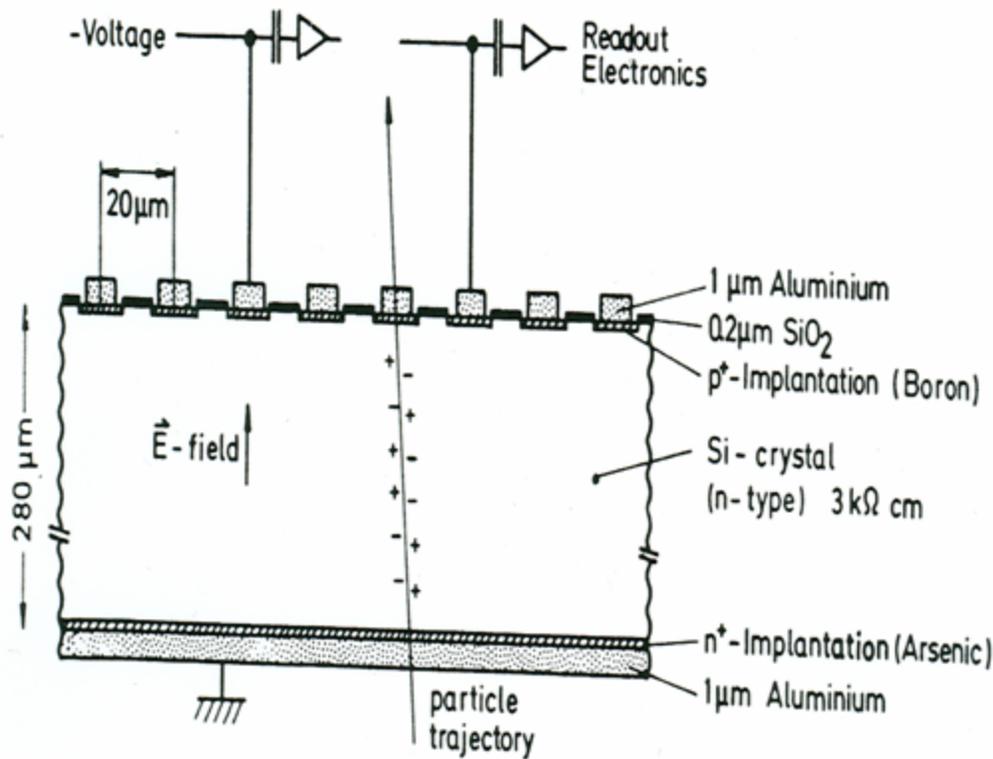


Table 1

Characteristics of the TUM-MPI-CERN silicon detectors

Material	3 k Ω cm n-doped Si single crystals
Size	2 inch Ø, 280 μm thickness
Radiation length	$3 \times 10^{-3}$
Depletion voltage	120 V
Number of e-h-pairs for a min. i. particle	24 000
Number of strip diodes	1 200
Strip pitch	20 μm
Length of strips	36 mm
Sensitive area	$24 \times 36 \text{ mm}^2$
Number of read out strips	240
Pitch of read out strips	$60 \mu\text{m}^{\text{a)}$ $120 \mu\text{m}^{\text{b)}$
Spatial accuracy	$4.5 \mu\text{m}^{\text{a)}$ $7.9 \mu\text{m}^{\text{b)}$
Two particle resolution	$60 \mu\text{m}^{\text{a)}$ $120 \mu\text{m}^{\text{b)}$

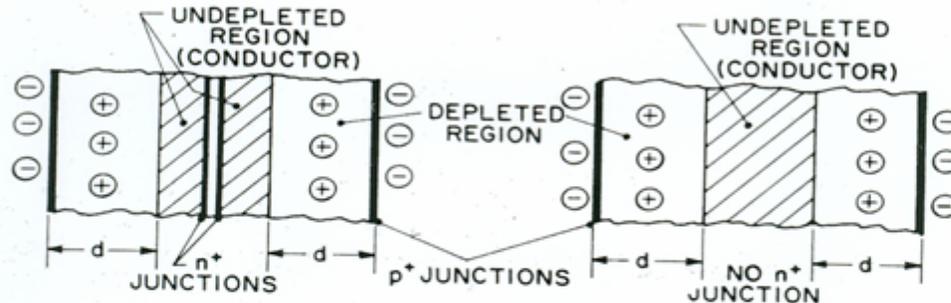
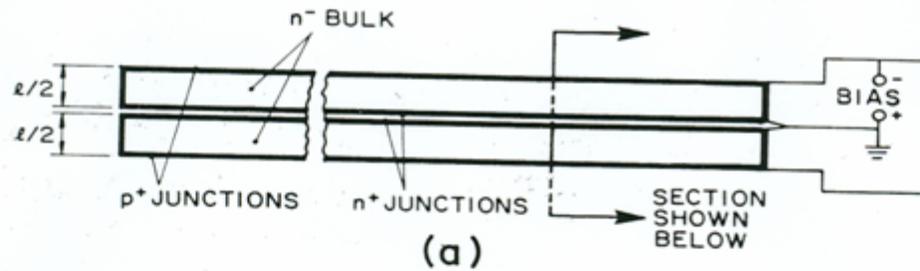
<sup>a)</sup> Central part of the detector;

<sup>b)</sup> Outer parts of the detector.

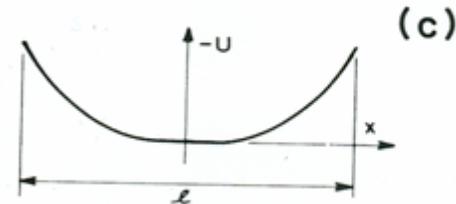
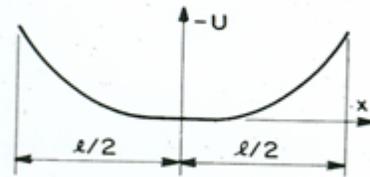
# New Types of Silicon Detectors

- Linear silicon drift detectors mainly for position sensing
- Cylindrical drift detectors with extremely small capacitance as X-ray or optical photon detectors
- Fully depleted Charge Coupled Devices (CCD)
- Controlled Drift Detectors
- Etc.

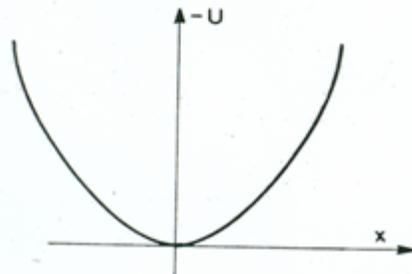
# Storage of charge in bulk of silicon



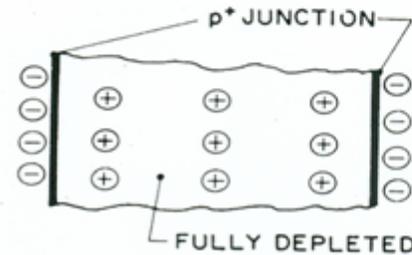
(b)



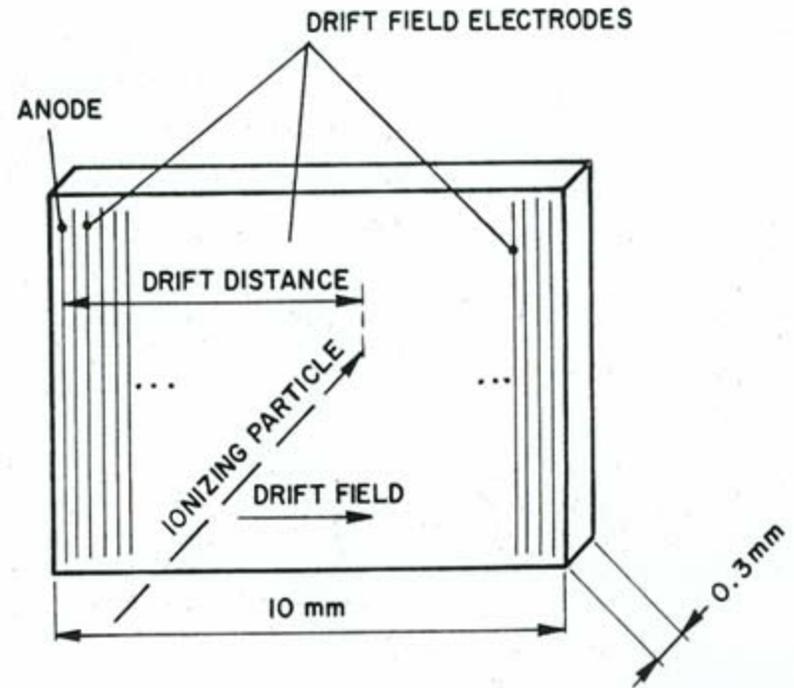
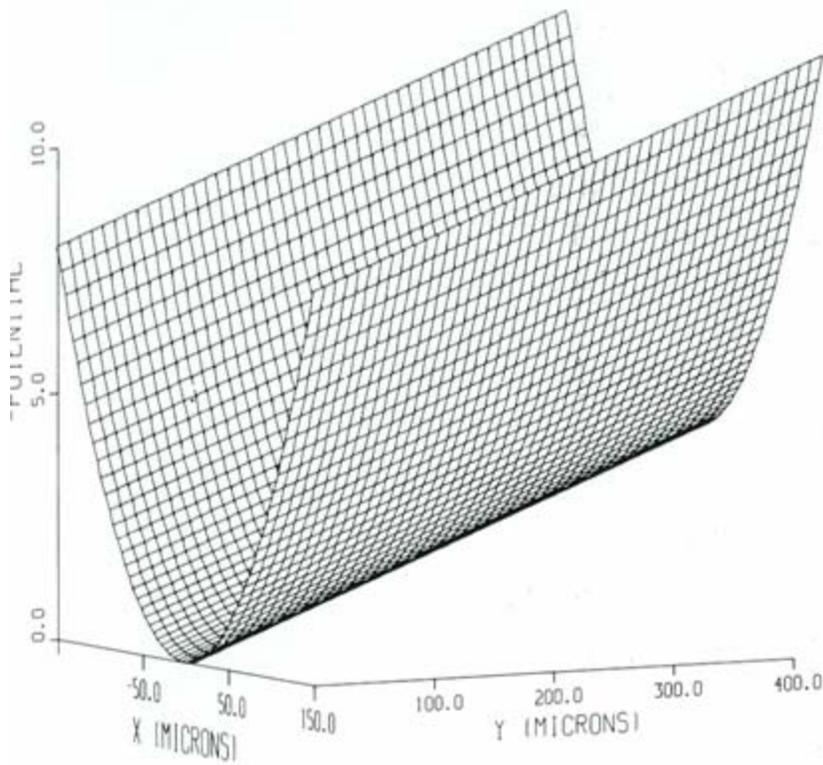
(c)



(d)

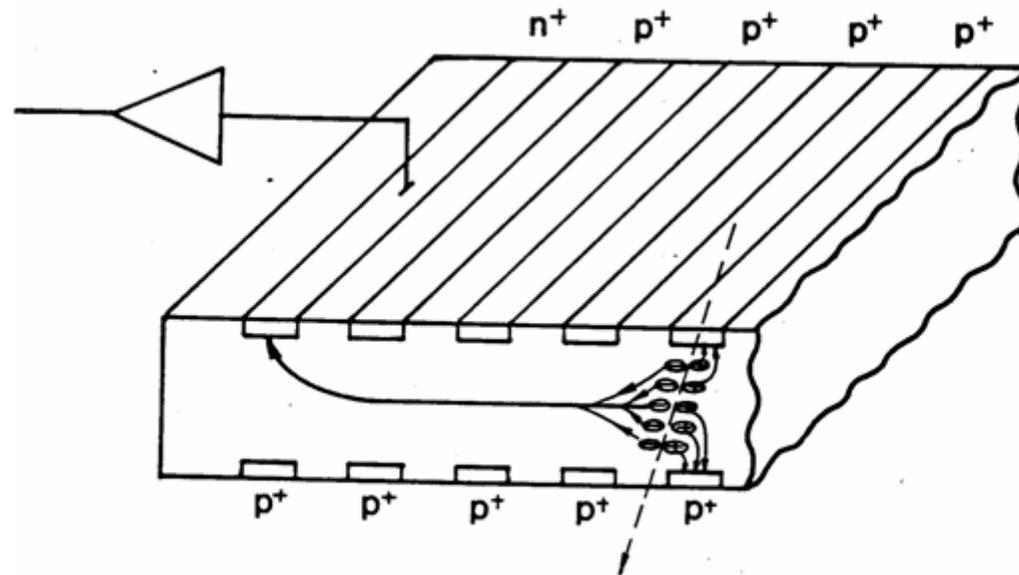


# Principle of linear drift silicon detector (mainly for position determination)



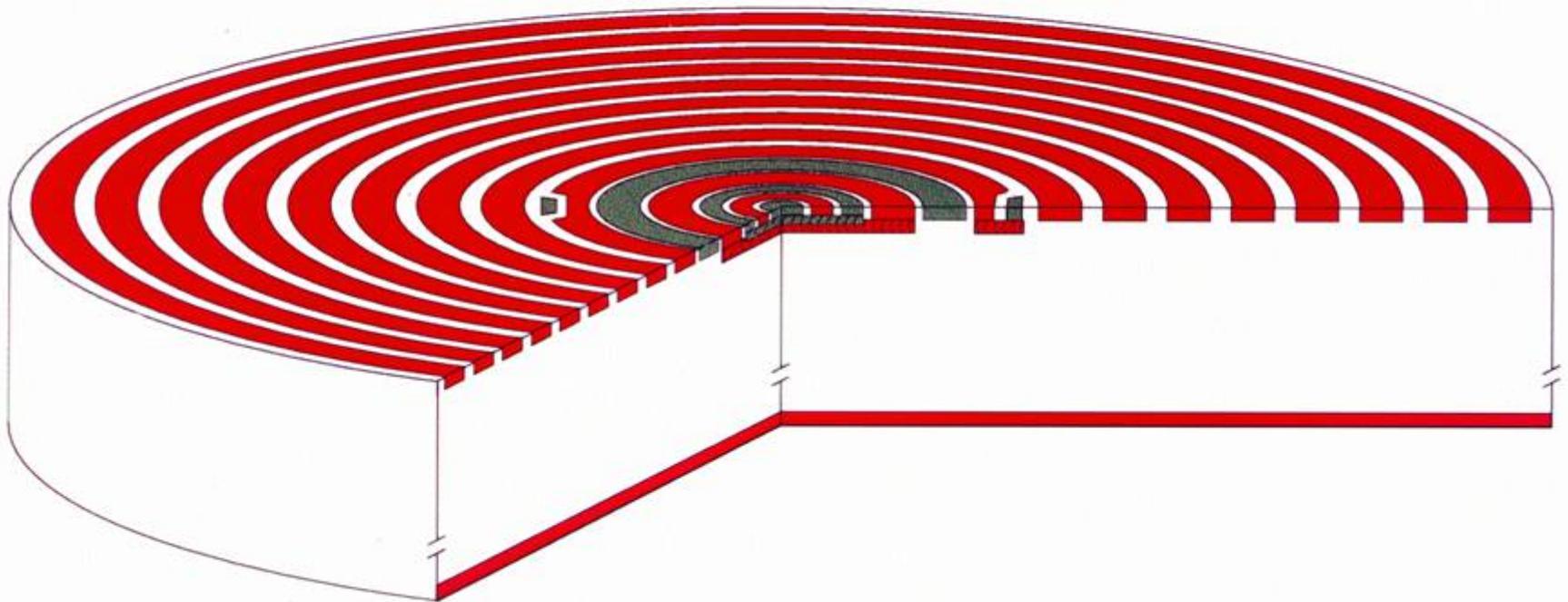
... the lateral field along the y axis is

# Linear drift detector with segmented rectifying electrodes

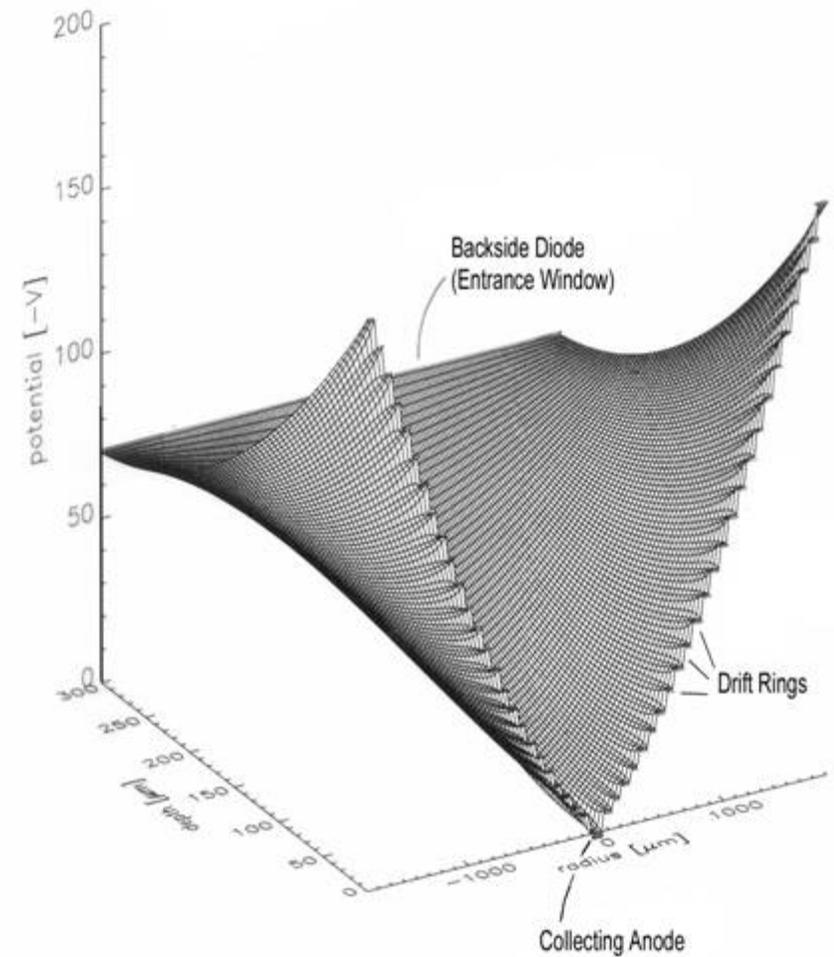
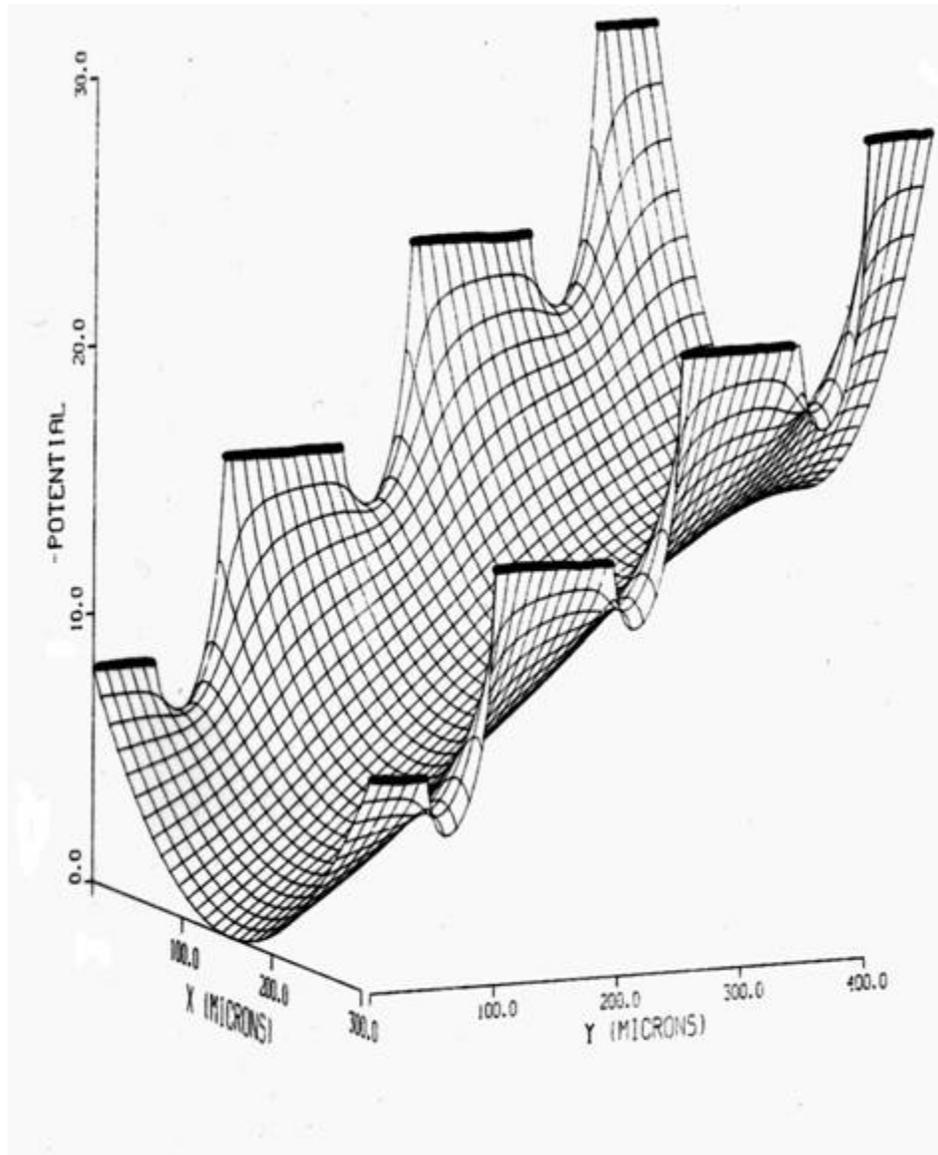


# X-ray drift detector

*Silicon Drift Chamber*

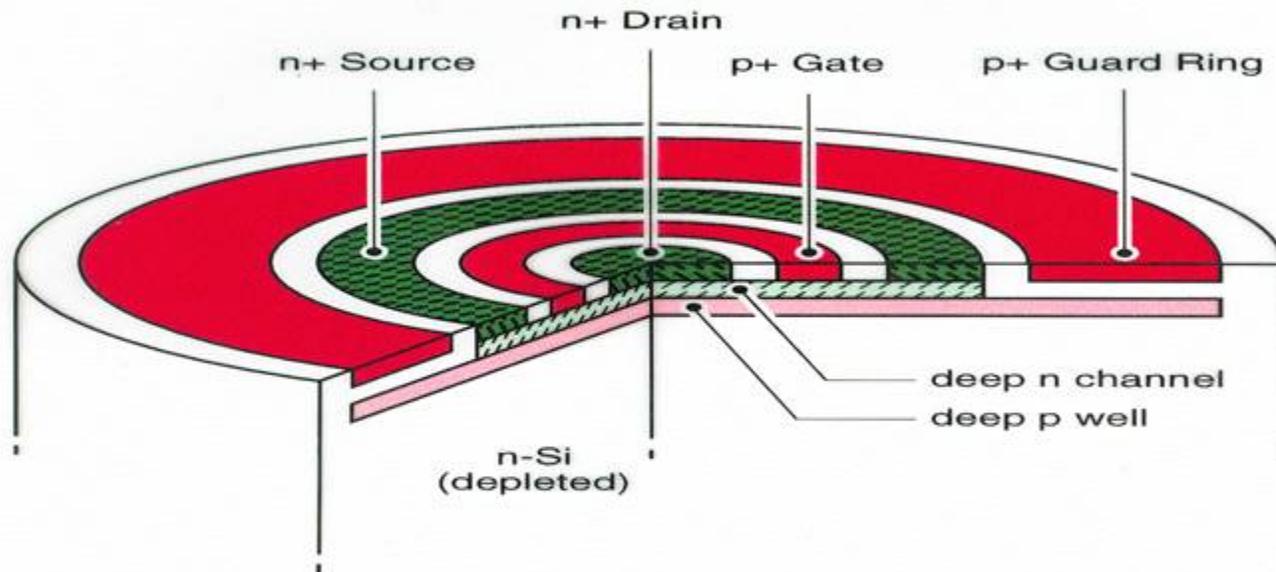


# Potential within Drift Detectors



# Single sided junction FET

N-Channel JFET on Depleted N-type Silicon



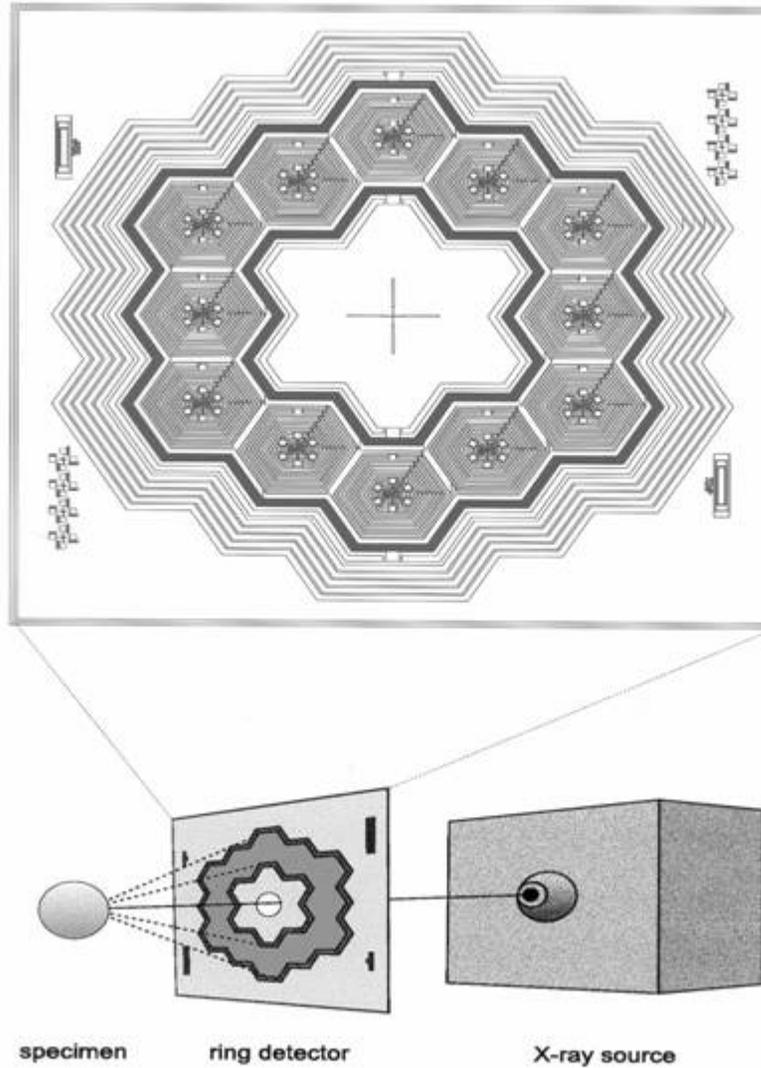
size & characteristics (typical):

gate length	5 $\mu\text{m}$
gate width	50 $\mu\text{m}$
saturation current	400 $\mu\text{A}$
transconductance	400 $\mu\text{A/V}$

# X-ray fluorescence system

Multi Channel SDD

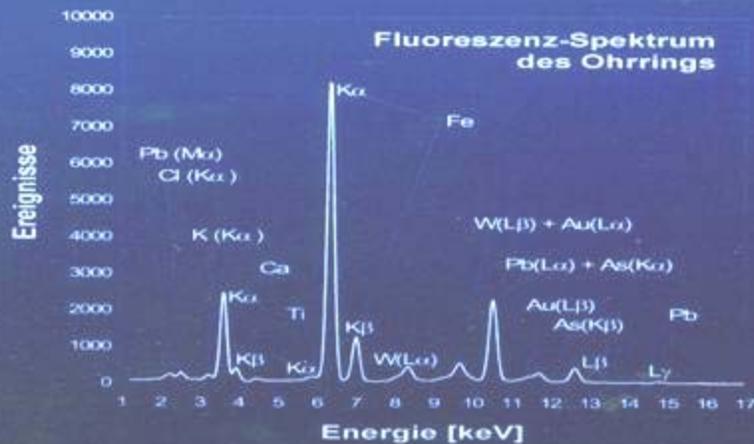
ring detector for compact XRF systems



# Applications in Art studies

## XRF-Analyse (X-Ray Fluorescence)

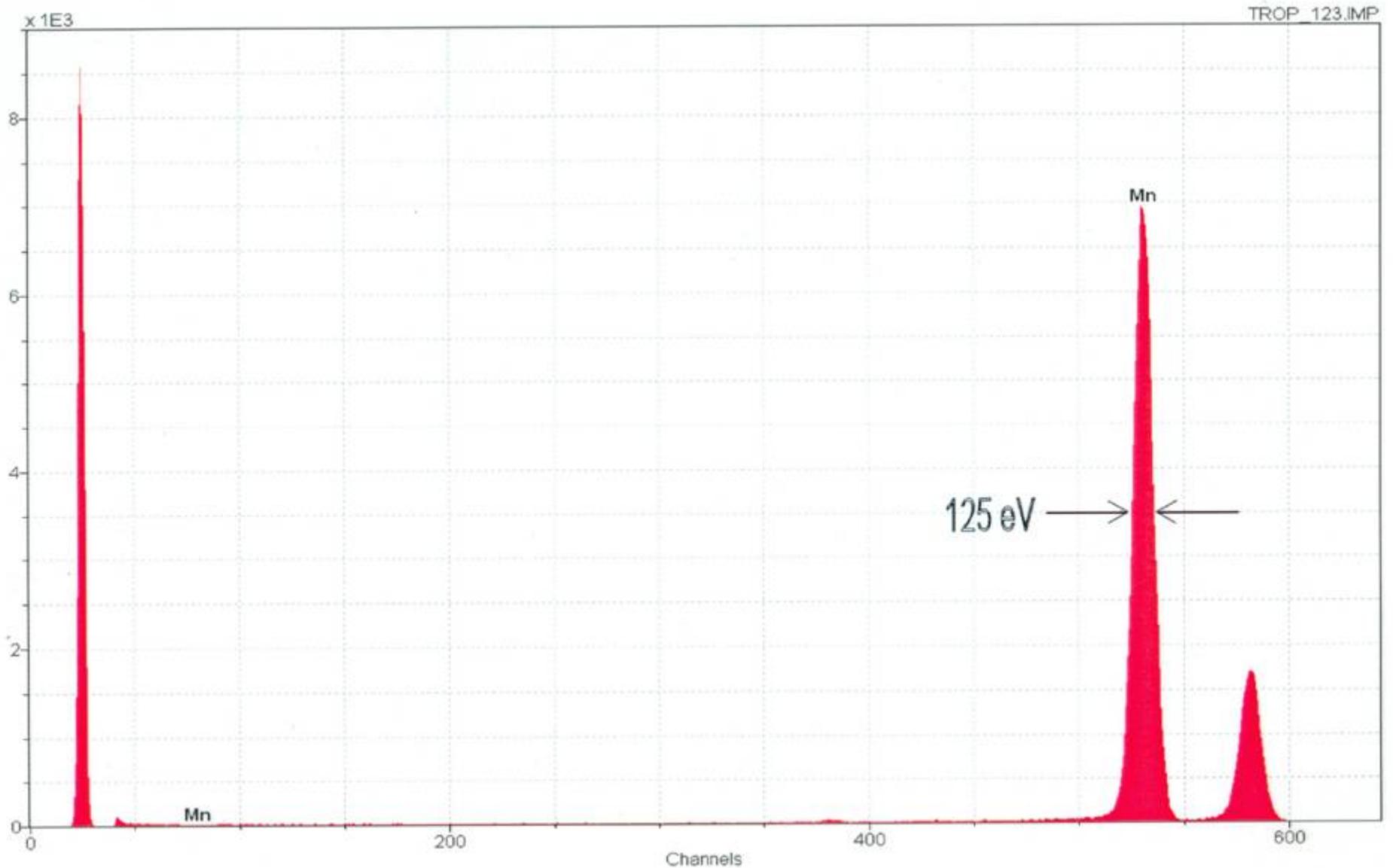
Untersuchung eines Leichentuchs  
(Antinopolis, III. Jahrhundert n. Chr., Vatikanische Museen)



Photographie des Detektor-Moduls

Die Farbe besteht aus einer Mischung von Orpiment ( $\text{As}_2\text{S}_3$ ) und Goldstaub.

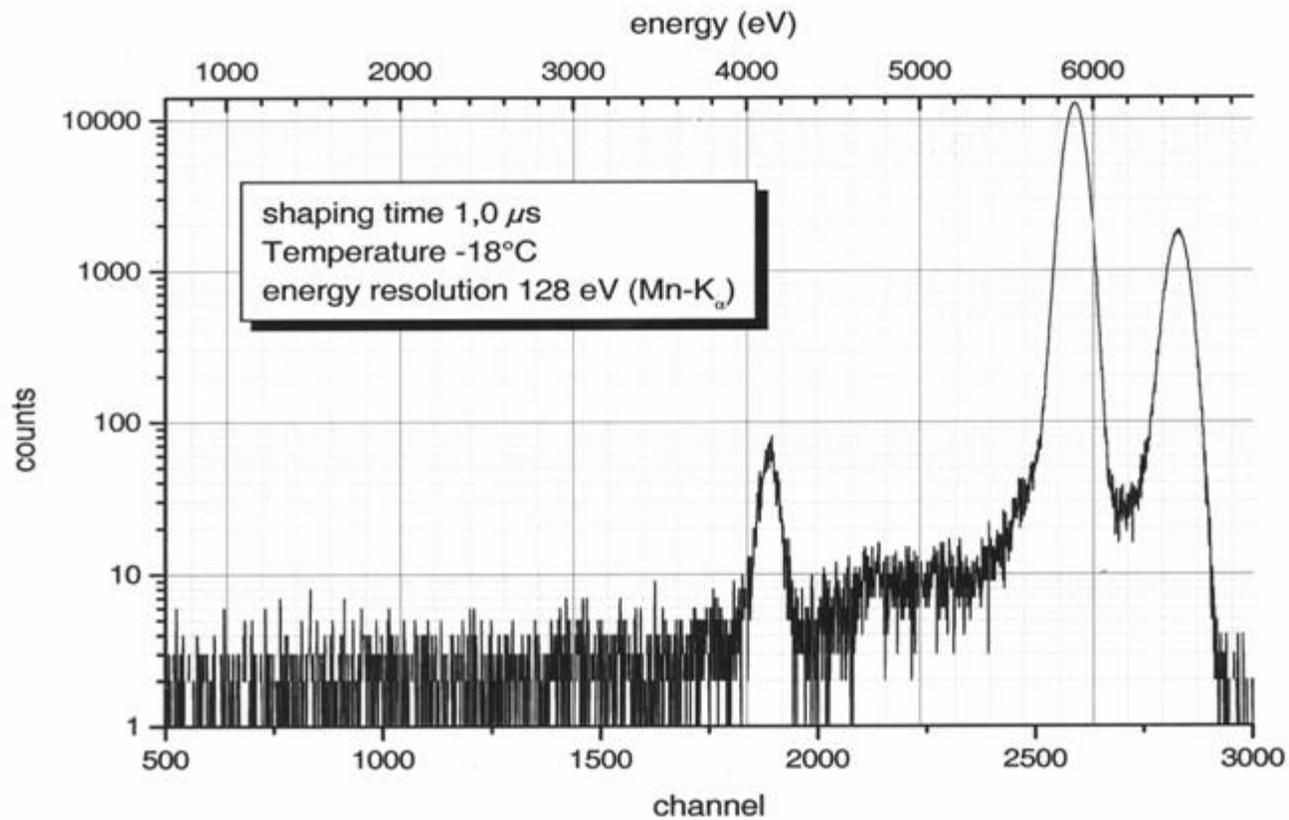
# The best room temp. spectrum



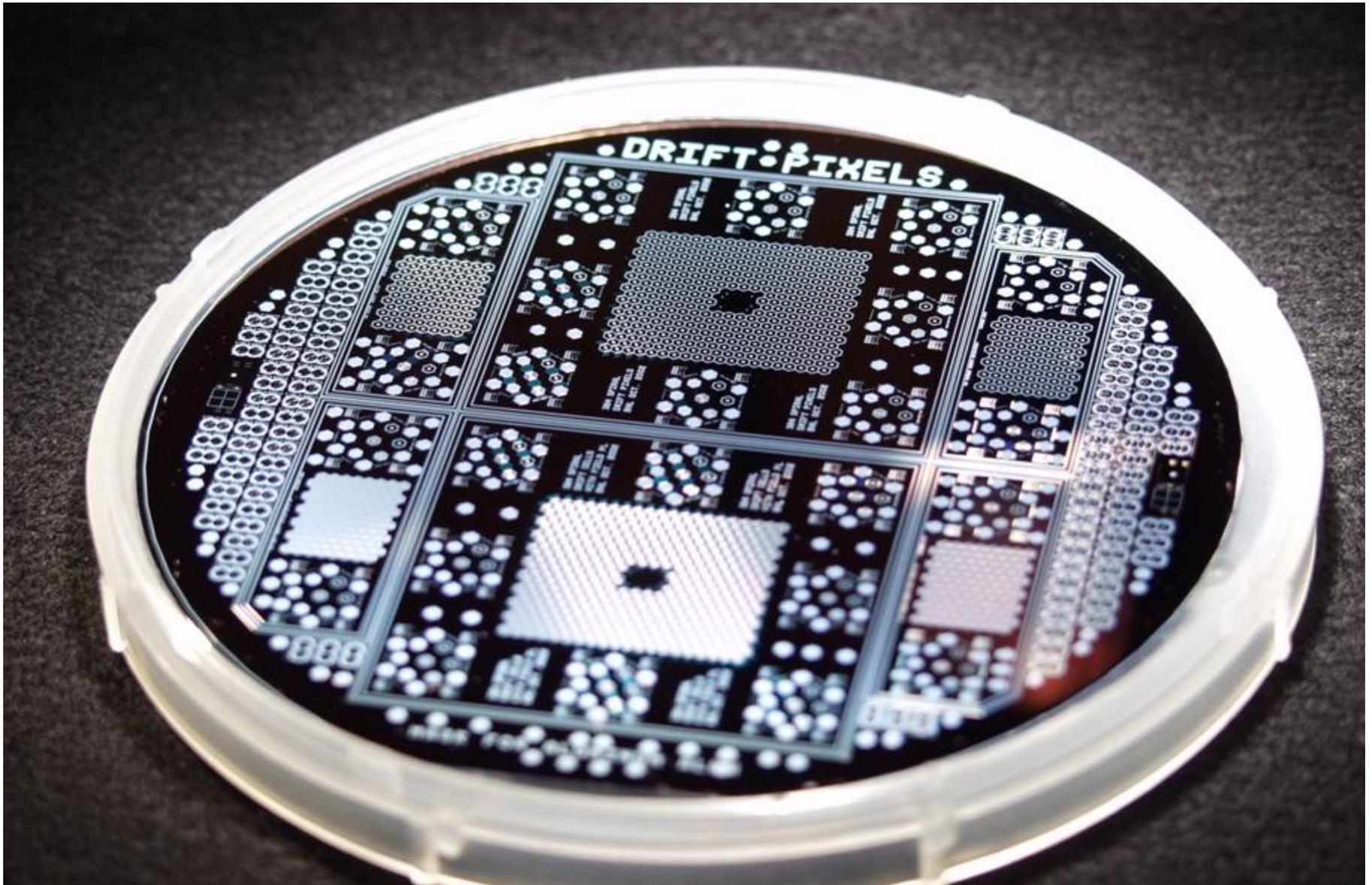
# Low energy tails



## Spectral Response

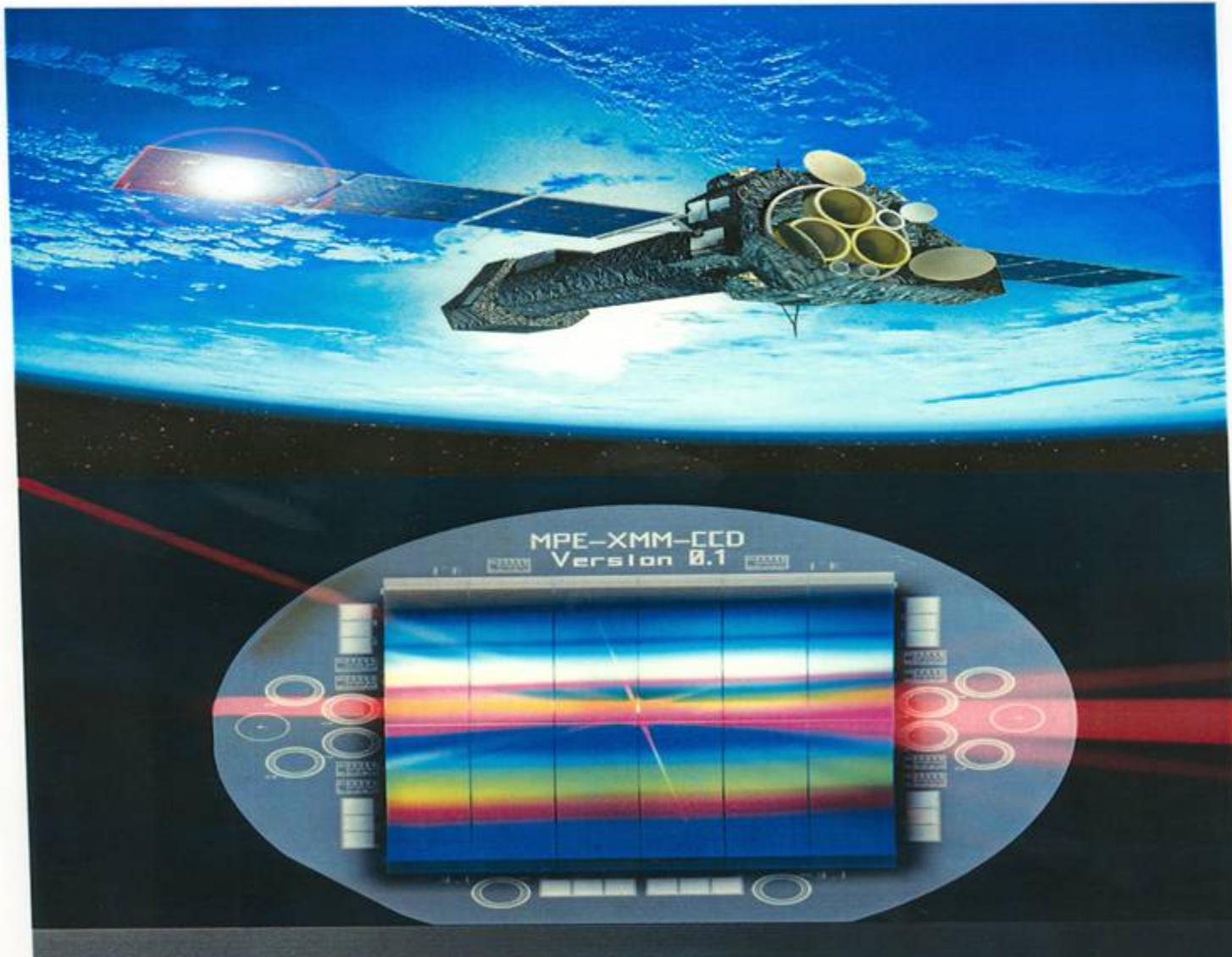


# Very high rate applications



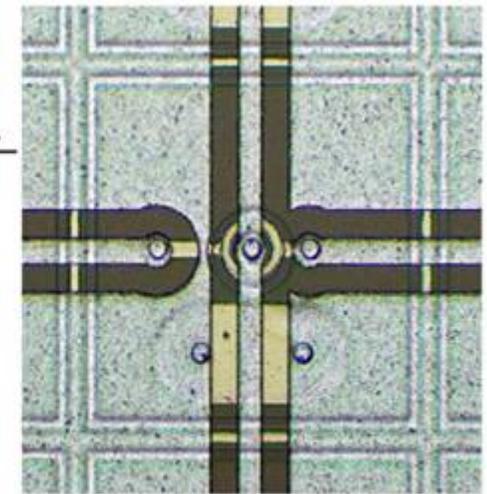
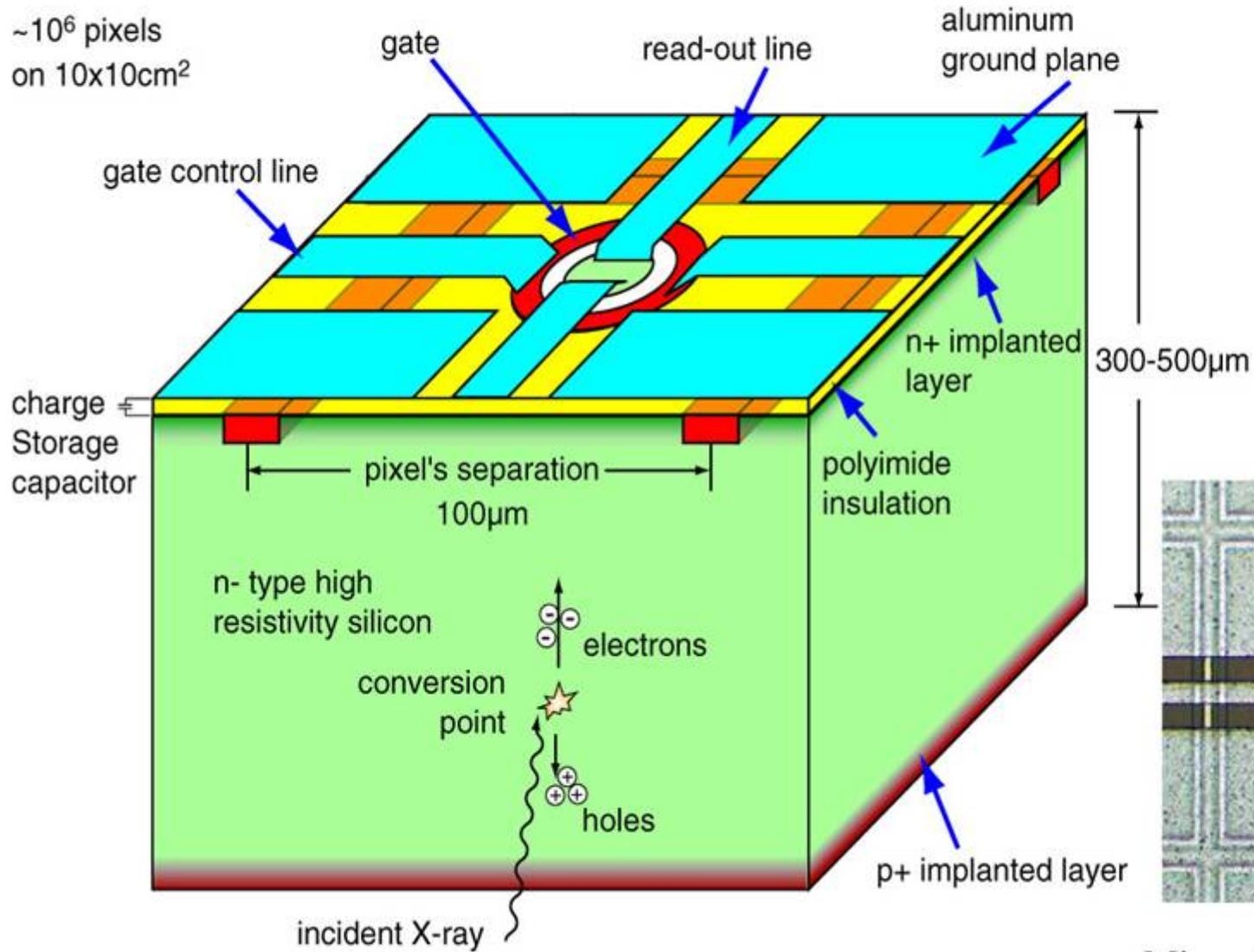
# Fully depleted CCD

The pn-CCD on the XMM Observatory



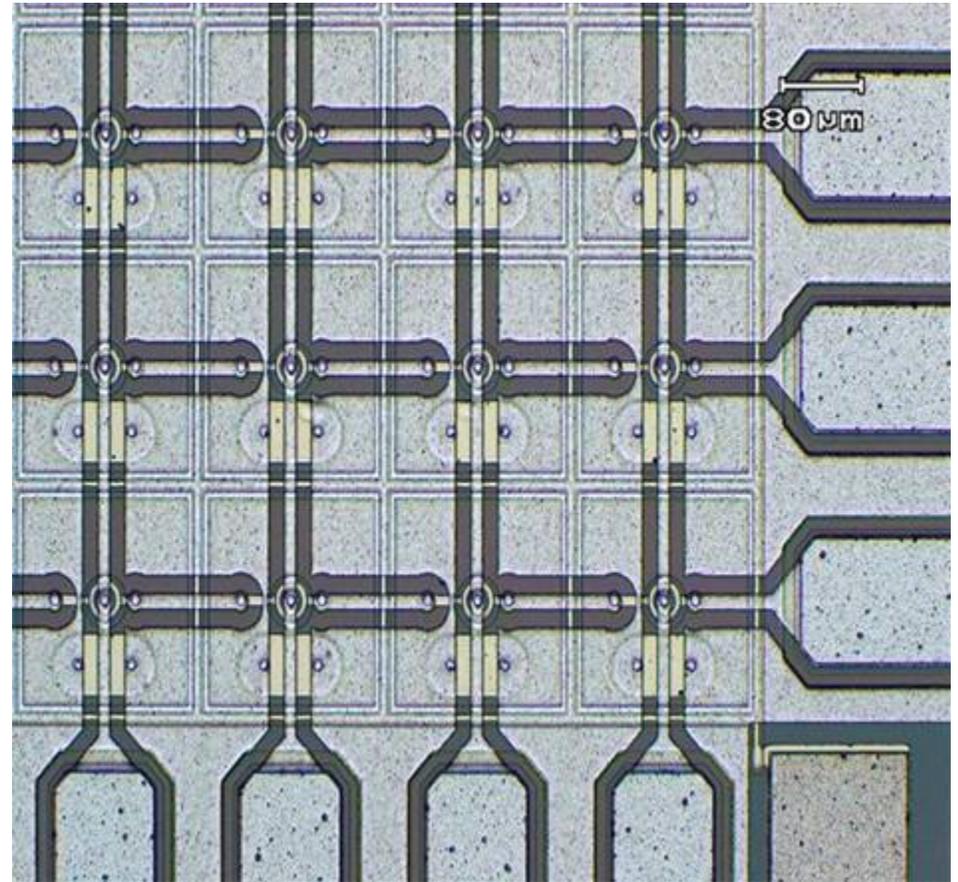
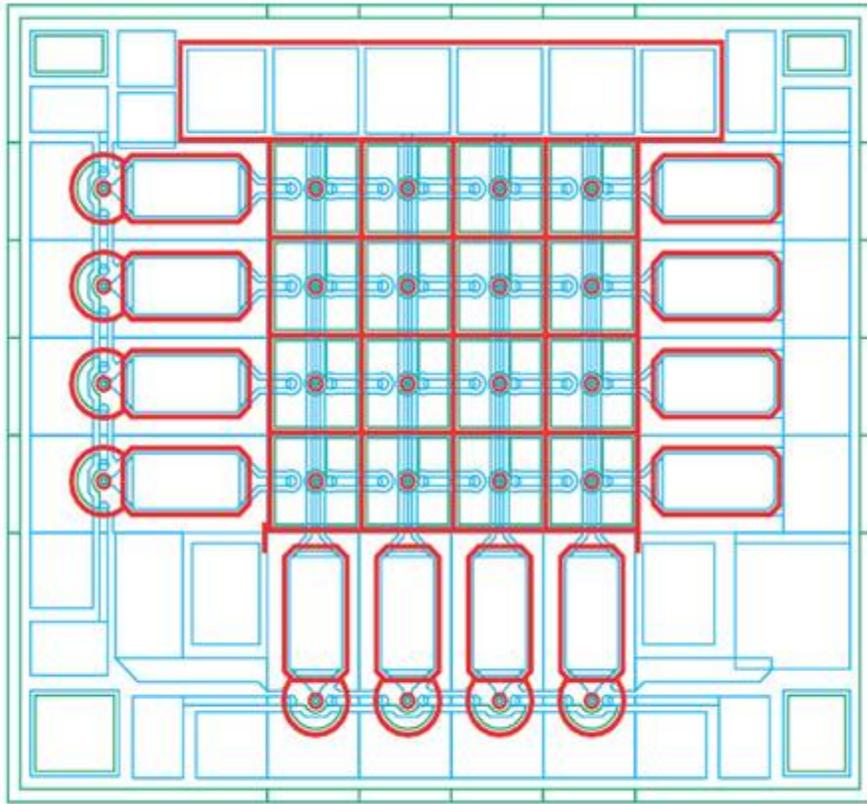
# 3D View of an X-ray Active Matrix Pixel

$\sim 10^6$  pixels  
on  $10 \times 10 \text{ cm}^2$

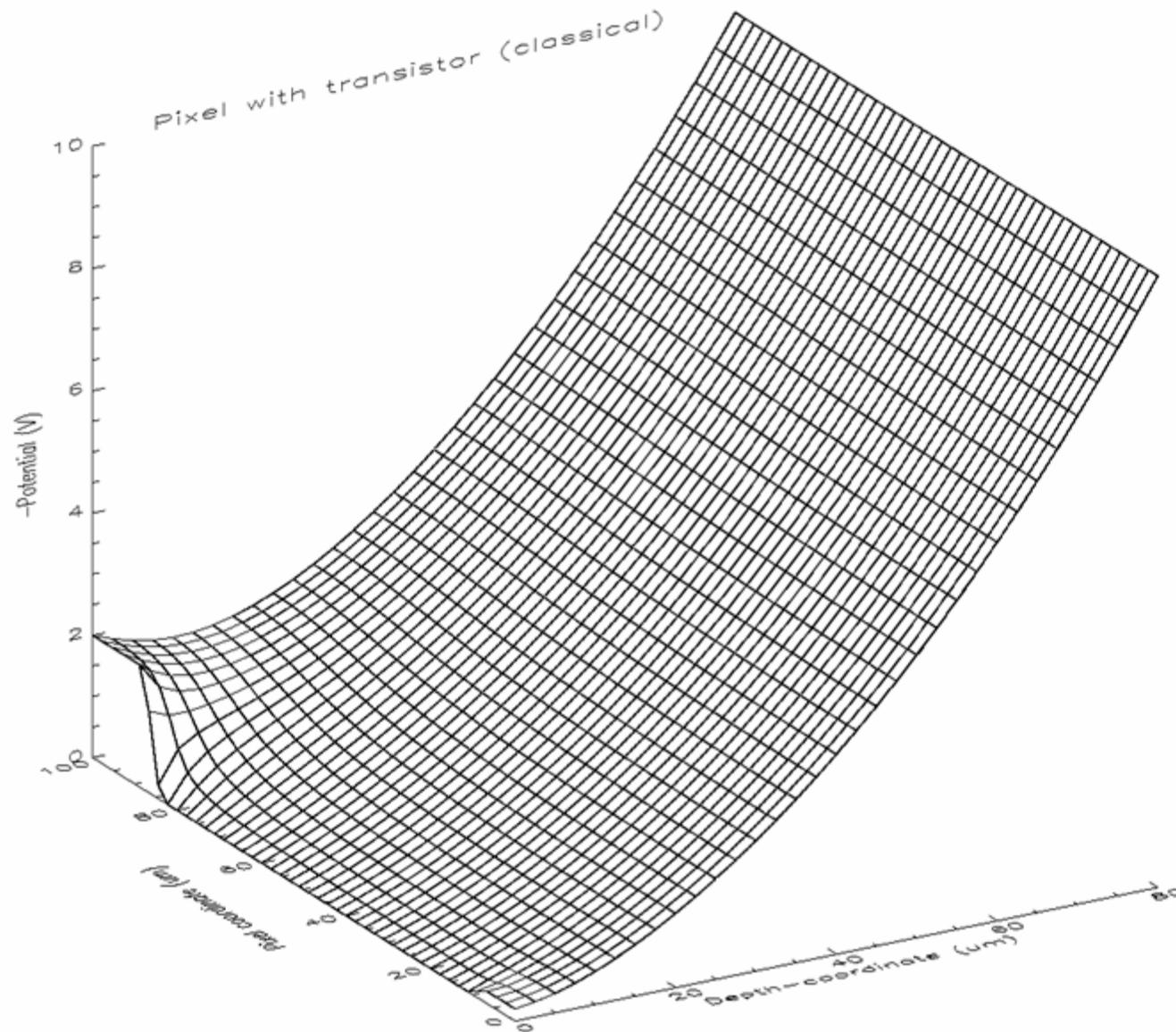


Microphotograph of a pixel

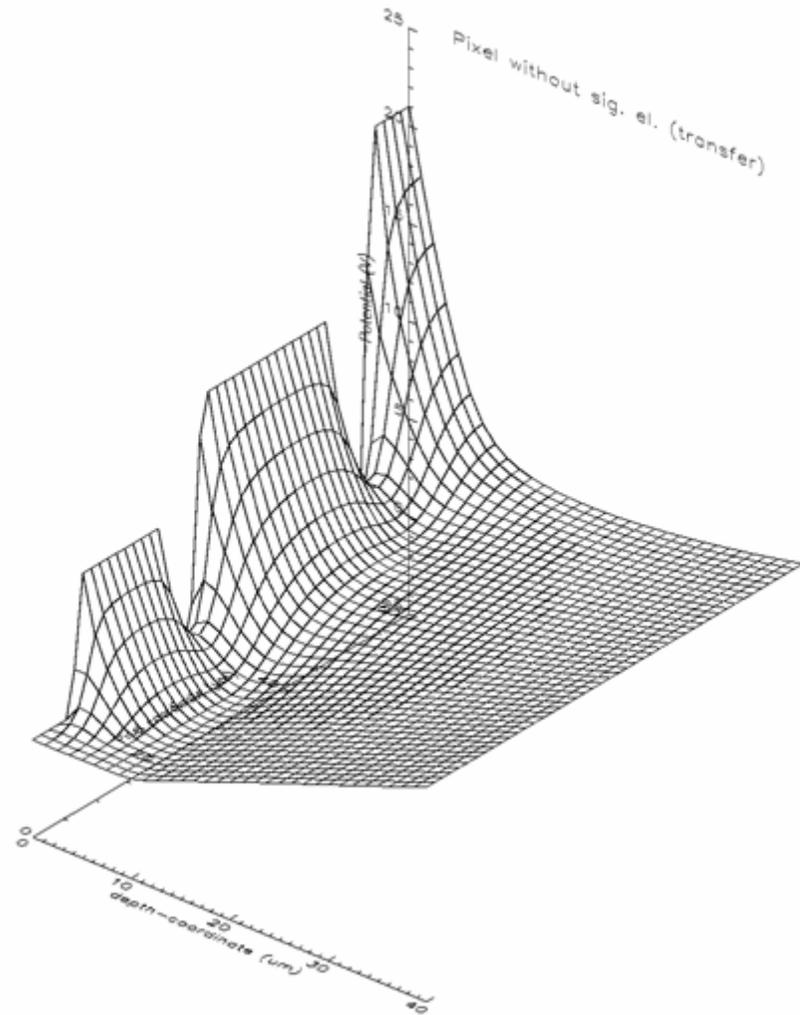
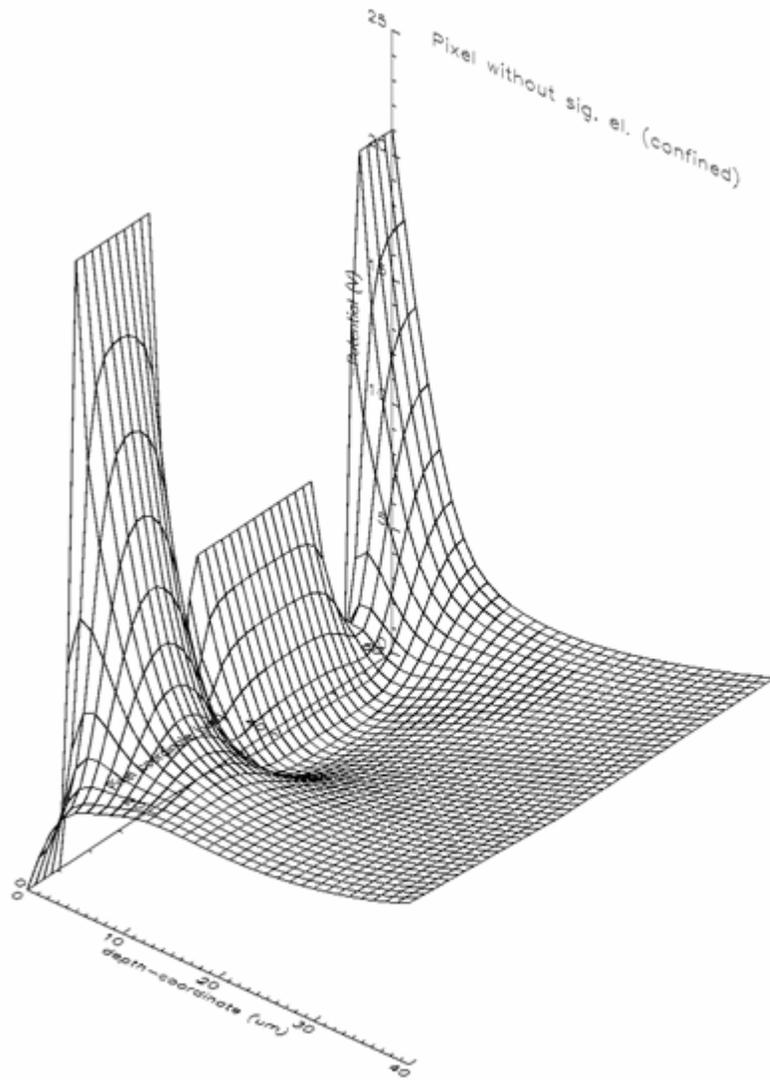
# Planar view of XAPMS

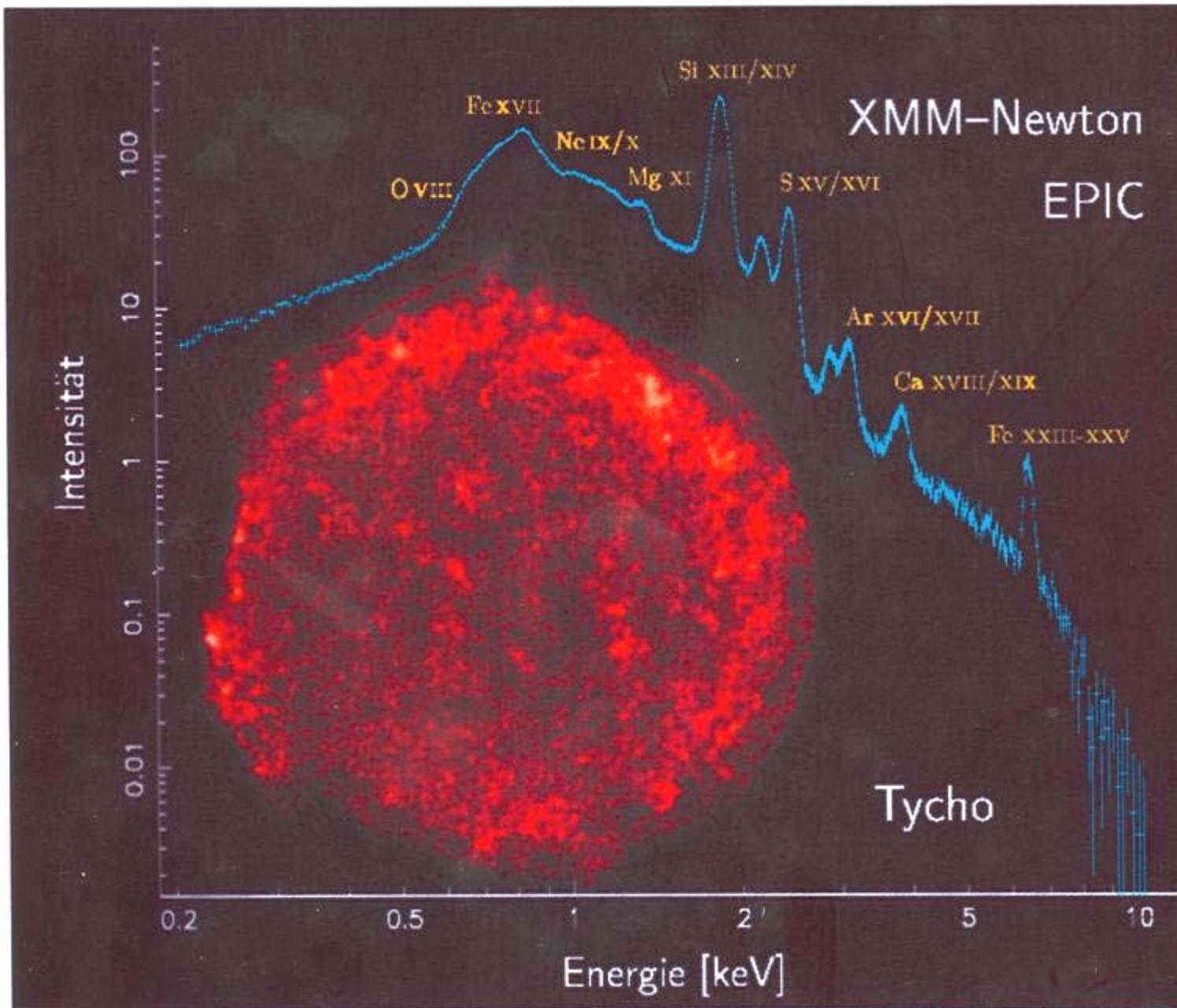


# Electric field in classical XAPMS



# Electric field in new XAMPS & FDCCD





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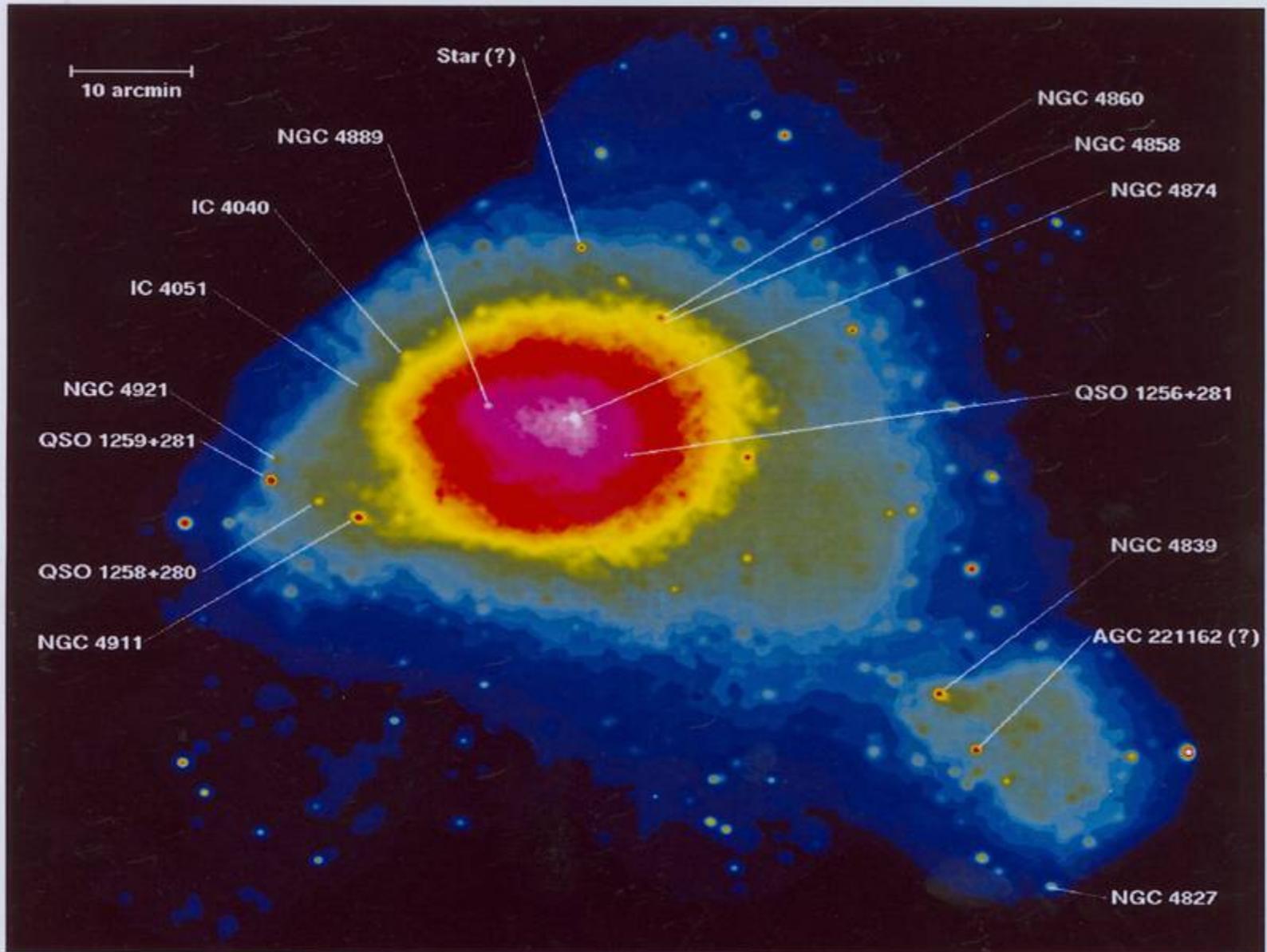
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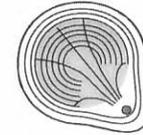
[EPIC-pn image \(0.5-2.0keV\) of SDSS 1044-0125](#)

in the energy band from 0.3 to 2.0 keV (U. G. Briel et al.)  
surface brightness distribution after smoothing with 2-dim Gaussians



# Planar technology vs lithium

## Performance of SD<sup>3</sup>



	SDD	Si(Li)	SD <sup>3</sup>
<b>FWHM</b> @ 1-10 kcps	142 – 147 eV @ - 10° C 138 – 142 eV @ - 20° C	130 eV @ LN	127 – 135 eV @ - 10° C 124 – 132 eV @ - 20° C
<b>FWHM</b> @ 100 kcps	180 eV	-----	170 eV
<b>P/B-Ratio</b>	3.000 – 5.000	10.000 – 20.000	6.000 – 7.000 homogenously
<b>Active Area</b>	5 and 10 mm <sup>2</sup>	10 (30, 80) mm <sup>2</sup>	5 mm <sup>2</sup> → 10 - 30 mm <sup>2</sup>
<b>Sensitive Thickness</b>	0.3 mm	4 mm	0.3 mm → 0.5 mm
<b>Stability</b>	good radiation hard	sometimes critical	op.stab. improved rad.hard. improved

# Summary & Conclusions

- Silicon is the ideal detection medium from 1 eV to 10keV of photon energy
- The progress in production technology make silicon detectors almost room temperature detectors
- The silicon prepared by standard CMOS processing technology may in a near future replace several traditional detector structures